



CERTIFICATE

OF EXCELLENT ARTICLE

Nanomanufacturing and Metrology

Takes great pleasure in presenting this award to

HIRAKU MATSUKUMA, RYO ISHIZUKA, MASAYA FURUTA, XINGHUI LI, YUKI SHIMIZU & WEI GAO

**Reduction in Cross-Talk Errors in a Six-Degree-of-Freedom
Surface Encoder**

as the Excellent Article contributed to
the NMME Journal in 2020.

A blue ink signature of Fengzhou Fang, written in a cursive style.

FENGZHOU FANG
EDITOR-IN-CHIEF

A blue ink signature of Wei Gao, written in a cursive style.

WEI GAO
EXECUTIVE EDITOR